



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : Customer Number: 20277
 Shinya TOKUNAGA, et al. : Confirmation Number: 4744
 Application No.: 10/722,346 : Group Art Unit: 2825
 Filed: November 26, 2003 : Examiner: SIEK, VUTHE

For: MASK PATTERN INSPECTING METHOD, INSPECTION APPARATUS, INSPECTING DATA USED THEREIN AND INSPECTING DATA GENERATING METHOD

Mail Stop Amendment
 Honorable Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

Dear Sir:

Transmitted herewith is an Amendment in the above-identified application.

- No additional fee is required.
 Applicant is entitled to small entity status under 37 CFR 1.27
 Also attached: Replacement Drawings for Figures 25, 26A and 26B

The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	Fee
Total Claims	19	26	0	\$50.00 =	\$0.00
Independent Claims	1	5	0	\$200.00 =	\$0.00
Multiple dependent claims newly presented				\$0.00	
Fee for extension of time				\$0.00	
				\$0.00	
Total of Above Calculations				\$0.00	

- Please charge my Deposit Account No. 500417 in the amount of \$0.00. An additional copy of this transmittal sheet is submitted herewith.
- The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 500417, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

McDERMOTT WILL & EMERY LLP

Michael E. Fogarty
 Registration No. 36,139

Please recognize our Customer No. 20277 as our correspondence address.

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 Date: November 16, 2005
 WDC99 1162803-1.061282.0048



Docket No.: 061282-0048

PATENT

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AMENDMENT UNDER 37 C.F.R. § 1.111

Mail Stop Amendment
Honorable Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to Office Action dated August 16, 2005, having a shortened statutory period for response set to expire on November 16, 2005, please amend the above-identified application as follows: